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The perfect answer to all your measurement needs

# The NEXIV VMR series

With an expanded lineup that includes small to ultra-wide measurement platforms as well as versatility in optical head selection, the NEXIV VMR series provides complete support for all your measurement needs.

-	Туре	Ultra High Precision	Small Parts	Ultra Wide	Ultra Wide
	XY stroke (mm)	300×300	150×150	1000×800	1200×720
	51	VMR-H3030	VMR-1515	VMR-10080	VMR-12072
for Type 1, 2, 3		Master Instruments for measurement room Molds	Packages Substrates Pressed parts Small parts (connectors, etc.) Watch components Car metal parts	Printing mask for substrates LCD parts	Large flat panel display parts
		VMR-H3030 Z120X	VMR-1515 Z120X	VMR-10080 Z120X	VMR-12072 Z120X
Maximum Magnification Module (VMR-Z120X)		WL-CSPs WL-Bump height WL-SIPs Rerouted masks MEMS masks	Small high-density substrates Small high-precision molds Packages (2D + height) MEMS parts	LCD glass substrates (pattern measurement) Organic EL glass substrates (pattern measurement)	LCD glass substrates (pattern measurement) Organic EL glass substrates (pattern measurement)
	1		VMR-1515 LU	VMR-10080 LU	VMR-12072 LU
LU Head (LU Model)	UN C		Small LCDs Semiconductor wafers (smaller than 150 mm)	Large LCDs Color filters	Large LCDs Color filters
Iltra High Precision Mea			asurement Platform VMR-1515		
nodel can serve as	cision and versatility, t the master instrumen MR-H3030 achieves s	t in your 150 x 150 x	515 series has a smaller travel (X, Y x 150. le for metrology automation of si	brilliantly in the me	nm stage stroke performs easurement of large-size

• A long 50mm working distance sufficiently supports

High-speed TTL Laser AF ensures high-precision AF

5X zoom provides wide field of view for rapid search and

high magnification for accurate measurement. Accurate

calibration at all magnifications allows rapid field of view

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measurements of 3D workpieces

measurements of multiple parameters

independent of surface shape.

- I ong stage stroke enables measurements of I CD substrates/modules and large-size PCBs
- Laser AF also enables measurements of height variance and warping in workpieces
- Search function facilitates measurements of lands and holes of PCBs
- Variety of illumination choices facilitate accurate edge detection even for vague geometries
- High-speed stage and high-speed image processing provide high throughput

# Optical Head for Type 1, 2, 3

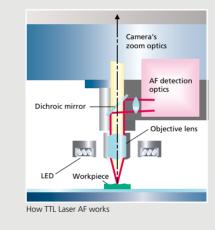
Ensure measurements with high accuracy and at high speeds.

# Widefield, high N.A. objective lens

The highly corrected objective lens is equivalent to those found in Nikon's top-end microscopes. They have a high N.A. of 0.35 with a long 50mm working distance at all magnifications.

# **Upgraded TTL Laser AF**

TTL Laser AF provides high resolution, long working distances, and fast operating speed for perfect focusing on narrow spaces at low magnifications. High-speed scanning measurement is possible at a rate of 1000 points per second max., enabling ultra-precise Z-axis measurements in a variety of applications.



# Standard head with 15X high-speed zoom

The standard head features 5-step, 15X high-speed zoom, providing greater flexibility in choosing magnifications according to the size of the measuring area.

#### Magnification vs field of view (mm)

Zoom position	1	2	3	4	5
Туре 1					
Optical magnification	0.5×	1×	2×	4×	7.5×
Total magnification	18×	36×	72×	144×	270×
Field of view (mm)	9.33×7	4.67×3.5	2.33×1.75	1.165×0.875	0.622×0.467
Туре 2					
Optical magnification	1×	2×	4×	8×	15×
Total magnification	36×	72×	144×	288×	540×
Field of view (mm)	4.67×3.5	2.33×1.75	1.165×0.875	0.582×0.437	0.311×0.233
Туре 3					
Optical magnification	2×	4×	8×	16×	30×
Total magnification	72×	144×	288×	576×	1080×
Field of view (mm)	2.33×1.75	1.165×0.875	0.582×0.437	0.291×0.218	0.155×0.117

Total magnifications listed above represent those on the monitor screen when a 24" monitor is set to the UXGA (1600 x 1200 pixels) mode.

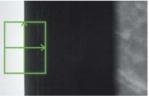
micrometer level uncertainty thanks to optimum layout of the ultra-precise low-thermal expansion glass scales and robust hardware designs.

- Ultrahigh precision appropriate for the Master Instrument
- Wide illumination choices ensure accurate detection of edges in dies and molds
- Long working distance (50mm) permits measurement of parts with large height variance
- 15X zoom provides wide field of view for rapid search and high magnification for accurate measurement. Accurate calibration at all magnifications allows rapid field of view measurements of multiple parameters

# High-speed, high-precision Vision AF

Thanks to the adoption of a new algorithm and a progressive scan CCD camera, Vision AF now provides greater speeds and accuracy closer to TTL Laser AF. Vision AF is convenient for applications where TTL Laser AF cannot be used, for example, when focusing on chamfered or round edges. The Multiple-Vision AF enables the simultaneous measurement of multiple points with different heights within the field of view.



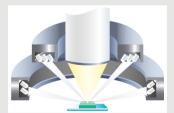


Surface focus

Edge focus

# 8-sector LED ring illumination

An illumination system consisting of inner and outer ring illuminators has been specially developed for the VMR series. The system makes possible observations of extremely low-contrast edges which are usually invisible under episcopic illumination by arbitrarily combining illuminations from eight directions. Best for edge enhancement of the contours of bosses, pins, ceramic packages, and similar workpieces.



How the 8-sector LED ring illuminator works

### Inner ring illuminator

(37° from the optical axis)

This type can be universally used whenever strong illumination from various directions is needed. This illumination also provides a full 50mm working distance.

# **Outer ring illuminator**

(75° from the optical axis)

This type enables the observation of workpieces that are impossible with lighting at a shallow angle. When not in use, the illuminator retracts, creating more space over the workpiece. When in use, the working distance will be 10mm.



# Maximum Magnification Module VMR-Z120X

With variable magnifications up to 120x, these models address applications that demand higher precision and density.



### Newly developed maximum magnification module **VMR-Z120X**

The new module achieves a 1x to 120X magnification range by using two objectives and changing the optical path. An 8-step zoom gives this system the capability to do rapid field of view measurements of hundreds of parameters and do critical measurements of line widths down to 1µm.

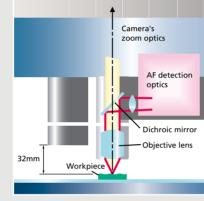
#### Magnification vs field of view (mm)

Optical magnification	1x	2x	4x	7.5x
Total magnification	36x	72x	144x	270x
Field of view (mm)	4.67 x 3.5	2.33 x 1.75	1.165 x 0.875	0.622 x 0.467
Optical magnification	16x	32x	64x	120x
Total magnification	576x	1146x	2292x	4320x
Field of view (mm)	0.291 x 0.218	0.146 x 0.109	0.073 x 0.055	0.039 x 0.029

Total magnifications listed above represent those on the monitor screen when a 20" monitor is set to the UXGA (1600 x 1200 pixels) mode.

### High-resolution TTL Laser AF with ultra tiny laser spot

The module comes with a high-resolution TTL Laser AF that incorporates high N.A. objectives and achieves ultra tiny laser spots. It significantly improves performance in focusing on and scanning over thin, transparent/semitransparent (e.g. resists) surfaces or irregular reflection surfaces. High-speed scanning measurement is possible at a rate of 1000 points per second max., enabling ultra-precise Z-axis measurements in a variety of applications.



How TTL Laser AF works

# LU Head (LU Model)

Universal epi-illuminator/motorized nosepiece type

Nikon's industry-acclaimed CFI60-2 optics supports high-precision, strain-free measurements.



# CFI60-2 optical system

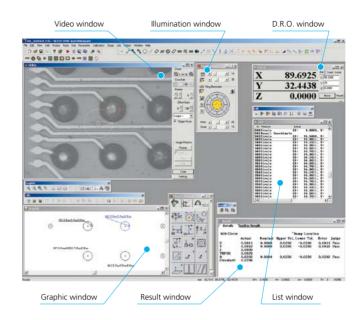
CFI60-2 optics, the culmination of Nikon's optical technologies, achieves brilliant, high-contrast images, making the system most suitable for the observation of large LCD substrates and color filters. This system can perform both dimensional measurements of a workpiece via image processing and observation in a single unit. By using a high-contrast DIC slider, enhanced DIC imaging is also possible.



CFI60-2 objective lenses	Magnification	NA	W.D. (mm)	CFI60-2 objective lenses	Magnification	NA	W.D. (mm)
	5x	0.15	18.00	TU Plan EPI ELWD*	20x	0.40	19.00
	10x	0.30	15.00		50x	0.60	11.00
TU Plan Fluor BD	20x	0.45	4.50		100x	0.80	4.50
bD	50x	0.80	1.00		10x	0.20	37.0
	100x	0.90	1.00	T Plan	20x	0.30	30.0
	20x	0.40	19.00	EPI SLWD*	50x	0.40	22.0
TU Plan BD ELWD	50x	0.60	11.00		100x	0.60	10.0
DD LLIVD	100x	0.80	4.50	TU Plan Apo EPI*	50x	0.80	2.00
CFI L Plan EPI*	2.5x	0.075	8.8		100x	0.90	2.00
T Plan EPI*	1x	0.03	4.0		150x	0.90	1.50
I FIdII EFI	2.5x	0.075	6.5	<b>TU D</b>	50x	0.80	2.00
	5x	0.15	23.50	TU Plan Apo BD	100x	0.90	2.00
T1 0 5	10x	0.30	17.50	60	150x	0.90	1.50
TU Plan Fluor EPI*	20x	0.45	4.50				
2	50x	0.80	1.00				
	100x	0.90	1.00				

# Standard Software

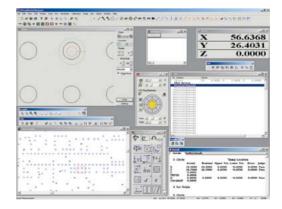
Main program



# CAD interface off-line teaching support program: **NEXIV Virtual AutoMeasure**

This program enables CAD data to be read into the Virtual Video Window on a separate computer, allowing the operator to use NEXIV's teaching program with the same operational procedures as on the online computer. This eliminates the necessity of using the actual workpiece during teaching sessions and lets the NEXIV system concentrate on automatic measurement for increased productivity.

- Supports IGES, DXF, DMIS, NC files, Gerber, and Excellon.
- The Virtual Video Window enables the operator to confirm the current field of view based on CAD data.
- Same operational procedures as the NEXIV AutoMeasure.
- Manual or one-click automated programming.
- Possible to combine programs with Macro steps, such as Line Width Measure and Multi Pattern Search

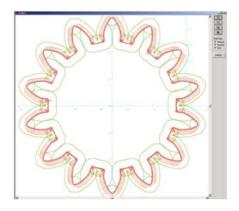


\*An LU objective adapter is necessary when using the EPI series of objective lenses.

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# Two-dimensional profile shape analysis program: **NEXIV Profiler/CAD Reader**

NEXIV Profiler makes it possible to measure and tolerance 2-dimensional profile shapes in a workpiece that cannot be measured in the normal geometric mode. Now more accurate quantitative measurements can be taken than with the chart comparison method using profile projectors and/or conventional measuring microscopes. With the NEXIV CAD Reader nominal shape data can be created from CAD data in the DXF/ IGES file format.



# Options

# Surface analysis software MountainsMap X

### Industry standard ISO/ASME/JIS compliant surface analysis software

The MountainsMap X is powerful software for surface metrology analysis. It provides the rich functionality of 3D visualization, cross-sectional view, 2D and 3D roughness, and other parameters based on the latest ISO standards.



# **EDF/Stitching Express**

This optional software makes EDF - Extended Depth of Field images by extracting focused pixel information from multiple captured images in Z-axis direction. Also, it generates stitching images from different FOV images captured with CNC XY stage motion, making a wide FOV observation possible. Both functions contribute to image documentation.



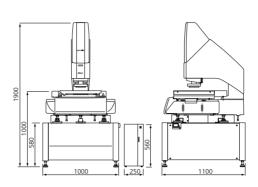
# Specifications

			Main Unit				
Model		VMR-H3030/Z120X	VMR-1515/Z120X/LU	VMR-10080/Z120X/LU	VMR-12072/Z120X/LU		
	Optical Head for Type 1, 2, 3 LU model	300 x 300 x 150 mm (11.8 x 11.8 x 5.9 in.)	150 x 150 x 150 mm (5.9 x 5.9 x 5.9 in.)	1000 x 800 x 150 mm (39.4 x 31.5 x 5.9 in.)	1000 x 800 x 150 mm (47.2 x 28.3 x 5.9 in.)		
Stroke	With max. magnification module (high mag. lens)	300 x 300 x 150 mm (11.8 x 11.8 x 5.9 in.)	150 x 150 x 150 mm (5.9 x 5.9 x 5.9 in.)	1000 x 800 x 150 mm (39.4 x 31.5 x 5.9 in.)	1200 x 720 x 150 mm (47.2 x 28.3 x 5.9 in.)		
	With max. magnification module (low mag. lens)	250 x 300 x 150mm (9.8 x 11.8 x 5.9 in.)	100 x 150 x 150 mm (3.9 x 5.9 x 5.9 in.)	950 x 800 x 150 mm (37.4 x 31.5 x 5.9 in.)	1150 x 720 x 150 mm (45.3 x 28.3 x 5.9 in.)		
Minimum read	out	0.01 µm		0.1 µm	1		
Maximum work	xpiece weight	30kg (66.1 lb)	20kg (44.0 lb) 40kg (88.2 lb) 40kg (8		40kg (88.2 lb)		
Measuring	U1x, U1y	0.6 + 2L/1000 μm (workpiece max. 10kg)	1.5 + 4L/1000 μm (workpiece max. 5kg)	2 + 4L/1000 µm (workpiece max. 40kg)	2.2 + 4L/1000 μm (workpiece max. 40kg)		
uncertainty	U <sub>2XY</sub>	0.9 + 3L/1000 μm (workpiece max. 10kg)	2.5 + 4L/1000 μm (workpiece max. 5kg)	3 + 4L/1000 μm (workpiece max. 40kg)	3.2 + 4L/1000 μm (workpiece max. 40kg)		
Z-axis (L: Lengt	n in mm < W.D.)	0.9 + L/150 µm	1.5 + L/150 µm 1	Note: Z-axis accuracy is guarant	eed by Laser AF.		
Camera			B&W 1/3-in. CCD (progressi	ve scan), color 1/3-in. CCD			
	Optical Head for Type 1, 2, 3	50mm					
Working distance	With max. magnification module	High mag. objective lens: 9.8mm Low mag. objective lens: 32mm					
	LU model	Varies depending on objective lens in use					
	Optical Head for Type 1	0.5 – 7.5X / 9.33 x 7 – 0.622 x 0.467 mm					
	Optical Head for Type 2	1 – 15X / 4.67 x 3.5 – 0.311 x 0.233 mm					
Magnification vs field of view	Optical Head for Type 3	2 – 30X / 2.33 x 1.75 – 0.155 x 0.117 mm					
	With max. magnification module	1 – 120X / 4.67 x 3.5 – 0.039 x 0.029 mm					
	LU model	Varies depending on objective lens in use					
Auto focus		TTI Laser AF and Vision AF. LU model: Vision AF only					
	Optical Head for Type 1, 2, 3 Diascop		pic, episcopic, 8-segment LED ring illumination (inner ring / outer ring)				
Illumination	With max. magnification module	Episcopic, diascopic (with high mag. head only), darkfield illumination					
LU model		Diascopic, Episcopacy & Darkfield illumination					
Power source		AC100-240V ±10%, 50/60H					
Power consum	Power consumption Max. 11A (Standard		ype), 13A (Z120X type)	Max. 13A (Standard type), 15A (Z120X type)			
Dimensions & weight	Main unit only	915 x 1060 x 1300 mm, approx. 450kg (36.0 x 41.7 x 51.2 in., 992.1 lb.)	512 x 703 x 1200 mm, approx. 180kg (20.2 x 27.7 x 47.2in., 396.8lb.)	_	_		
	Main unit & table	1000 x 1100 x 1900 mm, approx. 570kg (39.4 x 43.3 x 74.8 in., 1256.6 lb.)	512 x 703 x 1200 mm, approx. 180kg (20.2 x 27.7 x 47.2 in., 396.8 lb.)	1530 x 2200 x 1750 mm, approx. 1500kg (60.2 x 86.6 x 68.9 in., 3306.9 lb.)	1734 x 2200 x 1750 mm, approx. 1600kg (68.3 x 86.6 x 68.9 in., 3527.4 lb		
	Controller	250 x 550 x 500 mm, approx. 31kg (9.8 x 21.7 x 19.7 in., 68.3 lb.)					
Footprint		2400 (W) x 1400 (D) mm (94.5 x 55.1 in.)	2100 (W) x 1100 (D) mm (82.7 x 43.3 in.)	2800 (W) x 2500 (D) mm (110.2 x 98.4 in.)	3000 (W) x 2500 (D) mm (118.1 x 98.4 in.)		

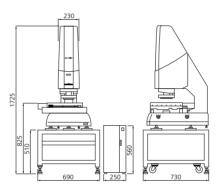
The "Z120X" type is equivalent to the "TZ" type in Japan.

# **Dimensional diagrams**

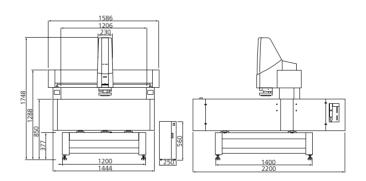
# VMR-H3030/Z120X



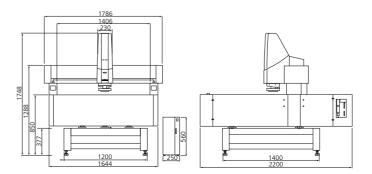
# VMR-1515/Z120X/LU



# VMR-10080/Z120X/LU

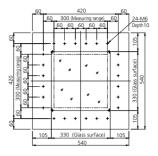


# VMR-12072/Z120X/LU

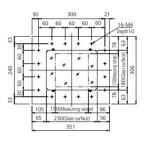


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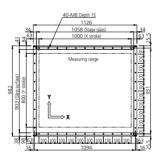
(Position of tapped holes for custom fixtures)



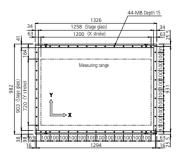
(Position of tapped holes for custom fixtures)



(Position of tapped holes for custom fixtures)



(Position of tapped holes for custom fixtures)



#### ISO/IEC 17025 Certified

Nikon Corporation Instruments Company has been certified as an ISO/IEC 17025 accredited calibration laboratory for CNC Video measuring systems by the Japan Accreditation Board for Conformity Assessment.

(ISO/IEC 17025: International standard, which specifies the general requirements to ensure that a laboratory is competent to carry out specific tests and/or calibrations)

Date of accreditation: Accredited section:

Calibration site:

November 22, 2010 Accredited section: Industrial Instruments CS 1st Engineering Section, Quality Assurance Department, Instruments Company Customer's laboratory (field service)

Type of measuring instruments: Coordinate measuring machine

ISO 9001 BUREAU VERITAS Certification

Scope of calibration	Maximum measuring abilities (K=2) [L=measurement length (mm)]	
nterval distance measurement	L ≤ 420mm	0.34µm
Interval distance measurement	420 ≤ L ≤ 1000mm	(0.45 + 0.54 x L/1000)µm

ISO 9001 Certified for NIKON CORPORATION

ents Company



Specifications and equipment are subject to change without any notice or obligation on the part of the manufacturer. February 2014 ©2014 NIKON CORPORATION

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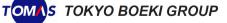
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